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JUN 1 2 2007

Application No.: 10/728,135

Docket No.: JCLA12578

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Examiner: Chacko Davis, Daborah

Group Art Unit: 1756

In re PATENT APPLICATION of
Applicants: Vencent Chang et al.

Serial No.: 10/728,135

Filed: December 03, 2003

For: IMMERSION LITHOGRAPHY
PROCESS AND MASK LAYER
STRUCTURE APPLIED IN THE SAME

## PRELIMINARY AMENDMENT

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Prior to the examination on merits, please amend the above-identified application as follows and consider the following remarks.

06/13/2007 TL0111 00000068 500710 10728135 02 FC:1251 120.00 DA

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